-2-

## AMENDMENT TO THE CLAIMS

- 1. (currently amended) A slider comprising:
  - a slider body having a trailing edge and a leading edge;
  - a thin film structure deposited in layers on the trailing edge, the structure comprising:
    - a write transducer configured to write data to a storage medium; and
    - a non-thermally activated actuator at least partially formed <u>coplanar</u> with the write transducer and configured to move the write transducer relative to the trailing edge.
- 2. (original) The slider of claim 1, wherein the actuator includes a stress field deposited in the layers of the thin film structure adjacent and with the write transducer, the stress field having a low stiffness layer interposed between a pair of high stiffness layers.
- 3. (original) The slider of claim 1, wherein the actuator comprises:
  - a yoke;
  - a conductive coil located within the yoke; and
  - an actuating material magnetically coupled to the yoke and conductive coil.
- 4. (original) The slider of claim 3, wherein the actuating material comprises one of a magnetostrictive material and a ferromagnetic shape memory alloy.
- 5. (original) The slider of claim 1, wherein the actuator comprises:
  - a pair of conductive contacts; and
  - an actuating material electrically coupled to the conductive contacts.
- 6. (original) The slider of claim 5, wherein the actuating material comprises one of a piezoelectric material and a magnetoelectric composite.
- 7. (original) The slider of claim 5, wherein the actuating material is deposited on the pair of conductive contacts such that the actuating material expands as a voltage is applied across the conductive contacts.

- 8. (original) The slider of claim 5, wherein the pair of conductive contacts are deposited on the actuating material such that the actuating material expands as a voltage is applied across the conductive contacts.
- 9. (original) The slider of claim 5, wherein the actuating material is deposited between the pair of conductive contacts such that the actuating material shears as a voltage is applied across the conductive contacts.
- 10. (original) The slider of claim 1, wherein the thin film structure further comprises a read transducer configured to read data from the storage medium, the read transducer formed and deposited adjacent the write transducer.
- 11 (original) The slider of claim 10, wherein the actuator is at least partially formed and deposited with the write transducer and the read transducer.
- 12. (original) The slider of claim 10, wherein the read transducer is deposited on the write transducer.
- 13. (original) The slider of claim 10, wherein the write transducer is deposited on the read transducer.
- 14. (original) The slider of claim 10 including a first compliant layer deposited prior to the write transducer.
- 15. (original) The slider of claim 14 including a second compliant layer deposited on one of the write transducer and the read transducer.
- 16. (original) The slider of claim 10 including a first compliant layer deposited prior to the read transducer.
- 17. (original) The slider of claim 16 including a second compliant layer deposited on the write transducer.
- 18. (currently amended) A method of manufacturing a slider, the method comprising:

4-

providing a slider body having a trailing edge and a leading edge;

forming a thin film structure deposited in layers on the trailing edge comprising:

forming a write transducer configured to write data to a storage medium; and

forming a non-thermally activated actuator at least partially coplanar with the write

transducer and configured to move the write transducer relative to the trailing

edge.

- 19. (original) The method of claim 18, wherein forming the thin film structure further comprises forming a stress field in layers adjacent and with the write transducer, the stress field having a low stiffness layer interposed between a pair of high stiffness layers.
- 20. (original) The method of claim 18, wherein forming the actuator further comprises: depositing an actuating material; and depositing a conductive coil positioned within a yoke, the yoke magnetically coupled to the conductive coil and the actuating material.
- 21. (original) The method of claim 20, wherein depositing the actuating material comprises depositing one of a magnetostrictive material and a ferromagnetic shape memory alloy.
- 22. (original) The method of claim 18, wherein forming the actuator further comprises: depositing a pair of conductive contacts; and depositing an actuating material electrically coupled to the conductive contacts.
- 23. (original) The method of claim 22, wherein depositing the actuating material comprises depositing one of a piezoelectric material and a magnetoelectric composite.
- 24. (original) The method of claim 18, wherein forming the thin film structure further comprises depositing a first compliant layer and a second compliant layer such that deformation of the write element is isolated and enhanced.
- 25. (original) A slider comprising:

-5**-**

- a slider body having a trailing edge and a leading edge;
- a thin film structure deposited in layers on the trailing edge, the structure comprising:
- a write transducer configured to write data to a storage medium; and
- a non-thermal actuator means formed at least partially coplanar with the write transducer for moving the write transducer in a direction perpendicular to a bearing surface and coupled to each of the arms of the first-named and second couplers.